

Riley Worstell

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ECE 542

HW #4

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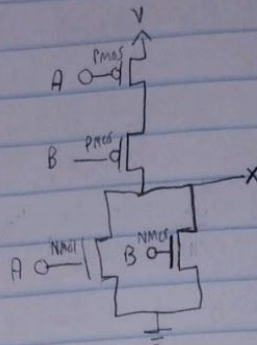
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Page #1

- ① Draw the schematic for a 2-input Nor Gate, using 2 NMOS & 2 PMOS transistors. This schematic sim to f05.4

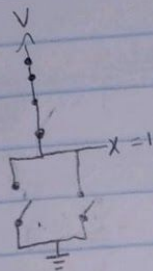
NMOS 1 flows, 0 shorts

PMOS 0 flows, 1 shorts

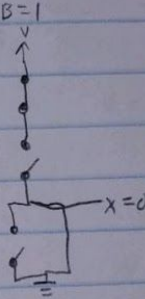


A	B	X
0	0	1
0	1	0
1	0	0
1	1	0

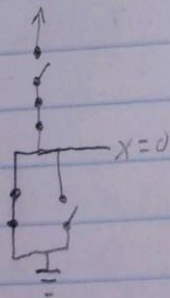
Case:  $A=0, B=0$



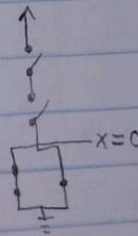
Case:  $A=0, B=1$



Case:  $A=1, B=0$



Case:  $A=1, B=1$



(2) A Silicon with Substrate  $N_A = 10^{17} \text{ cm}^{-3}$  is biased in such a way that it is in depletion. The depletion region width is  $0.1 \text{ nm}$ .

a) What is the volume charge density in depletion region,  $\text{C/cm}^3$ ?

$$\rho = -qN_A = -1.6 \cdot 10^{-19} \text{ C} (10^{17} \text{ cm}^{-3}) = -0.016 \text{ C/cm}^3$$

b) By integrating volume charge density, what is the surface charge density in  $\text{C/cm}^2$ ?

$$Q = SP = -0.016 \times (-0.016 \text{ C/cm}^3) (0.0001 \text{ cm}) = -1.6 \cdot 10^{-7} \text{ C/cm}^2$$

c) if the E-field drops to 0 at depth of  $0.1 \text{ nm}$ , what is the electric field at Silicon surface?

$$E(x) = \int_0^{0.1 \cdot 10^{-4}} \frac{\rho(x)}{\epsilon_0} dx = \int_0^{0.1 \cdot 10^{-4}} \frac{-0.016 \text{ C/cm}^3}{(8.85 \cdot 10^{-12} \text{ F/m})} (11.7) \left( \frac{1 \text{ m}}{10^9 \text{ nm}} \right) dx = 154522.2 \frac{\text{V}}{\text{cm}}$$

$(0.1 \cdot 10^{-6}) \text{ m} \left( \frac{10^9 \text{ nm}}{\text{m}} \right) = 0.1 \cdot 10^{-4} \text{ cm}$

$E_{\text{silicon}} = 11.7$

$= \frac{-0.016 \text{ C/cm}^3 (0.1 \cdot 10^{-4})}{(8.85 \cdot 10^{-12} \text{ F/m}) (10^9 \text{ nm/m}) (11.7)} + \text{break from 0}$

d) There is an  $\text{SiO}_2$  layer on top of Silicon. What is the E-field within the  $\text{SiO}_2$  layer? Note: you have to consider boundary between Si &  $\text{SiO}_2$ .

$$\epsilon_{\text{SiO}_2} = 3.9 \quad E_1 E_1 = E_2 E_2 \Rightarrow E_2 = \frac{\epsilon_1 E_1}{\epsilon_2} = \frac{11.7 (154522.2 \frac{\text{V}}{\text{cm}})}{3.9} = 463566.6 \frac{\text{V}}{\text{cm}}$$

e) A good quality layer of  $\text{SiO}_2$  can support an E-field of  $1.5 \text{ V/nm}$  before breakdown occurs. Does breakdown occur in  $\text{SiO}_2$  for this device?

$$1.5 \frac{\text{V}}{\text{nm}} > (463566.6 \frac{\text{V}}{\text{cm}}) \left( \frac{10^9 \text{ nm}}{\text{cm}} \right) \left( \frac{1 \text{ m}}{10^9 \text{ nm}} \right) = 0.04635666 \frac{\text{V}}{\text{nm}}$$

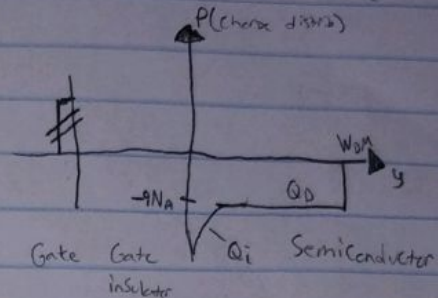
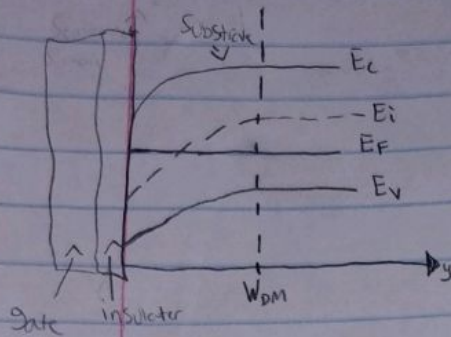
$\therefore$  there is no breakdown



(3) Make 2 graphs for NMOS Strong inversion. (a) Draw energy band diagram,

(b) draw Charge distribution vs distance

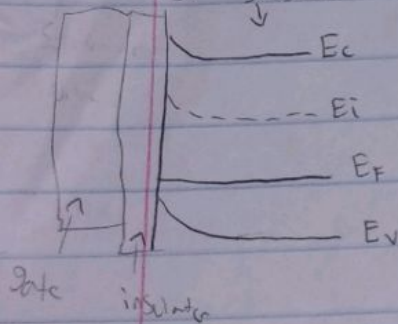
(a) NMOS Strong Inversion (Energy Band) (b) Charge distribution VS. distance



(4) Make 2 graphs NMOS Accumulation. (a) Draw energy band

(b) draw Charge distribution VS. distance.

(a) Substrate



(b) P(Charge distr.)

